



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Rand David Dannenberg
Title: Optical Coatings and Associated Methods
Application No.: 09/944,050 Filing Date: August 30, 2001
Examiner: Chang, Audrey V. Group Art Unit: 2872
Docket No.: VONA.004US0 Conf. No.: 8351

Certificate of Mailing Under 37 CFR 1.8

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Commissioner for Patents, Washington, D.C. 20231, on 2/11/04

Signature Eileen Bow

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P.O. Box 1450
Alexandria, VA 22313-1450

FEB 24 2004

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(c) WITH FEE**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying form PTO-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Listing of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or

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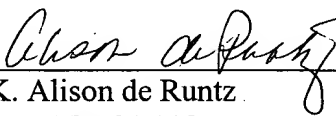
-1-

Serial No.: 09/944,050

3. an admission that the information listed herein is, or is considered to be, material to patentability as defined in § 1.56(b).

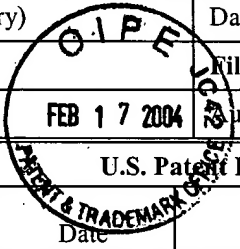
This information disclosure statement is submitted under 37 C.F.R. § 1.97(c). A check including \$180.00 for the information disclosure statement fee under 37 C.F.R. § 1.17(p), is enclosed. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

Respectfully submitted,



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U.S. Department of Commerce, Patent and Trademark				Atty. Docket No.		Application No.	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				VONA.004US0		09/944,050	
				Applicant(s)		Conf. No.	
(Use several sheets if necessary)				Dannenberg		8351	
				Filing Date		Group	
				August 30, 2001		2872	
U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	1	6,106,676	8/22/00	Terry et al.			
	2	6,514,620	2/4/03	Lingle et al.			
U.S. Published Patent Application Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
Foreign Patent Documents							
							Translation
		Document	Date	Country	Class	Subclass	Yes No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	3	P. A. Greene <i>et al.</i> , <i>Modeling of Production Scale Reactive Deposition of a Cylindrical Magnetron</i> , paper associated with an oral presentation made on April 18, 2000 at the 43 rd Annual Technical Conference Proceedings of the Society of Vacuum Coaters of April 15-20, 2000. Pre-prints of the paper were made available by the Society of Vacuum Coaters at the conference proceedings on April 17, 2000.					
	4	P. Greene <i>et al.</i> , <i>Model of Production Scale Reactive Deposition</i> , paper associated with an oral presentation made at the 42 nd Annual Technical Conference Proceedings of the Society of Vacuum Coaters of April 17-22, 1999. The oral presentation took place during the conference proceedings, although the precise date of the oral presentation is not known. It is believed that pre-prints of the paper were made available by the Society of Vacuum Coaters at some time during the conference proceedings. It is believed that copies of this paper were mailed by the Society of Vacuum Coaters to one or more unknown recipient(s) on a mailing date of August 22, 1999, but not before August 19, 1999.					
	5	P. Greene <i>et al.</i> , <i>Reactive Deposition and Material Properties of TiO_x ZnO_x</i> , paper associated with an oral presentation made on June 17, 1999 at conference proceedings of the International Symposium on Sputtering and Plasma Processes (ISSP) in June of 1999. Pre-prints of the paper were made available at some time during the conference proceedings.					
	6	R. Dannenberg <i>et al.</i> , <i>Reactive Sputter Deposition of Titanium Dioxide</i> , Thin Solid Films 360 (2000) 122-127, published on February 1, 2000.					
Examiner			Date Considered				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							